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ATTY. DOCKET NO. 8317-120-999 NOV 27 2001

APPLICATION NO. 09/876,944

APPLICANT

Bravo Vasquez and Hill

FILING DATE

June 8, 2001

GROUP

1762

LIST OF REFERENCES CITED BY APPLICANT

(Use several sheets if necessary)

U.S. PATENT DOCUMENTS

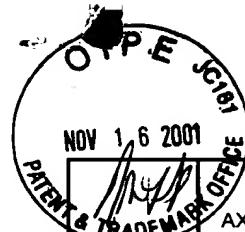
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
MPP	AA	4,952,556	08/28/90	Mantese et al.	505	1	
	AB	5,064,685	11/12/91	Kestenbaum et al.	427	53.1	
	AC	5,176,744	01/05/93	Muller	106	1.26	
	AD	5,277,980	01/11/94	Mino	428	403	
	AE	5,534,312	07/09/96	Hill et al.	47	533	
	AF	5,630,872	05/20/97	Ogi et al.	106	287.18	
	AG	5,696,384	12/09/97	Ogi et al.	252	182.12	
	AH	5,821,017	10/13/98	Thomson et al.	430	9	
MPP	AI	6,071,676	06/06/00	Thomson et al.	430	311	
MPP	AJ	6,126,855	10/03/00	Elliott	252	299.01	

FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	YES	NO
						YES		
MPP	AK DE 42 10 400 C1	01/07/93	Germany	Lapp			✓	
	AL EP 0 414 140 A2	02/27/91	Europe	Asano et al			✓	
	AM EP 0 670 055 B1	09/06/95	Europe	Thomson et al = AI = AH			✓	
	AN EP 0 687 136 A1	12/13/95	Europe	Brown et al			✓	
	AO JP 9-41159	02/10/97	Japan (English language abstract)	Mitsubishi Mat. Corp.			✓	
	AP JP 11-119431	04/30/99	Japan (English language abstract)	KOBE steel LTD			✓	
	AQ WO 90/02827	03/22/90	PCT	Tuff et al				✓
MPP	AR WO 94/11787	05/26/94	PCT	Thomson et al = AI = AH				

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MPP	AS	M. A. S Aquino, "Diruthenium and Diosmium Tetracarboxylates: Synthesis, Physical Properties and Applications," <i>Coord. Chem. Rev.</i> , 170:141-202 (1998). <i>no month</i>
	AT	A. A. Avey and R. H. Hill, "Solid State Photochemistry of $\text{Cu}_2(\text{OH}_2)_2(\text{O}_2\text{C}(\text{CH}_2)_4\text{CH}_3)_4$ in Thin Films: The Photochemical Formation of High-Quality Films of Copper and Copper(I) Oxide. Demonstration of a Novel Lithographic Technique for the Patterning of Copper," <i>J. Am. Chem. Soc.</i> , 118:1:237-238 (1996). <i>no month</i>
	AU	A. Beclaska, R. J. Batchelor, F. W. B. Einstein, R. H. Hill, and B. J. Palmer, "Solid-State Photochemistry and Structure of $\text{trans-(Et}_3\text{P)}_2\text{Ni}(\text{N}_3)_2$: Photodeposition of Nickel," <i>Inorg. Chem.</i> , 31:14:3118-3123 (1992). <i>no month</i>
	AV	D. G. Bickley, R. H. Hill, and C. I. Horvath, "Solid State Photochemistry of $(\text{C}_6\text{H}_{12})\text{Pt}(\text{N}_3)_2$ as Thin Films on $\text{Si}(111)$ Surfaces," <i>J. Photochem. Photobiol. A: Chem.</i> , 67:181-186 (1992). <i>no month</i>
MPP	AW	S. L. Blair, "Photochemical Deposition of Metal and Metal Oxide Films From Amorphous films of Inorganic Precursors," Ph.D. thesis, Simon Fraser University (1996). <i>December</i>



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AX	S. L. Blair, J. Hutchins, R. H. Hill, and D. G. Bickley, "Solid-State Photochemistry of Platinum(II) Methylazide Complexes as Thin Films on Si(111) Surfaces: Photolithography of Platinum Films," <i>J. Materials Sci.</i> , 9:2143-2146 (1994). <i>no month</i>
AY	S. L. Blair, W. Xia, and R. H. Hill, "The Photochemical Production of Nickel Films From Thin Films of the Inorganic Nickel Complexes $\text{trans-NiN}_4\text{X}_2$ ($\text{N}_2\equiv\text{Et}_2\text{NC}_2\text{H}_4\text{NH}_2$, $\text{MeHNC}_2\text{H}_4\text{NMeH}$; $\text{X}=\text{NO}_2$, NO_3 , NCS)," <i>J. Photochem. Photobiol. A: Chem.</i> , 91:183-191 (1994). <i>no month</i>
AZ	J. P. Bravo-Vasquez and R. H. Hill, "The Photolithographic Deposition of Nanostructured Materials," <i>Polymeric Materials Sci. and Eng.</i> , 81:16-17 (1999). <i>no month</i>
BA	C. W. Chu and R. H. Hill, "Solid State Photochemistry of Thin Films of Cr, Mo and W Organometallic Complexes as Thin Films on Silicon Substrates," Materials Research Society-Taiwan, <i>IUMRS-ICEM'94 Symp. Proc.</i> , Vol. 1, 441-446 (1994). <i>no month</i>
BB	L. B. Goetting, B. J. Palmer, M. Gao, and R. H. Hill, "Photoresist-Free Lithography of $3\ \mu\text{m}$ Wide UO_3 Lines From Amorphous Films of Uranyl Complexes," <i>J. Materials Science</i> , 29:6147-6151 (1994). <i>no month</i>
BC	R. H. Hill, A. A. Avey, S. L. Blair, M. Gao, and B. J. Palmer, "Molecular Design for Photo and Electron Beam Lithography With Thin Films of Coordination Compounds," <i>Materials Chemistry and Physics</i> , 43:233-237 (1996). <i>no month</i>
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BE	T. W. H. Ho, S. L. Blair, and R. H. Hill, "Solid State Photochemistry of $(\text{C}_2\text{H}_4(\text{Ph}_2\text{P})\text{M}(\text{N}_3)_2$ ($\text{M}=\text{Ni, Pd, Pt}$) on Si(111) Surfaces," <i>J. Photochem. Photobiol. A: Chem.</i> , 69:229-235 (1992). <i>no month</i>
BF	M. Ibn-Elha, D. Guillion, A. Skoulios, A. M. Giroud-Godquin, and P. Maldivi, "Structural Study of Crystalline and Columnar Copper (II) Soaps," <i>Liquid Crystals</i> , 11-5:731-744 (1992). <i>no month</i>
BG	B. J. Palmer, A. Becalska, T. W. H. Ho, and R. H. Hill, "Photolithography of Amorphous Films of $(\eta^5-\text{C}_5\text{H}_5)_2\text{Ti}(\text{N}_3)_2$ on Silicon (111) Resulting in TiO_2 : The Mechanism of the Photodeposition Reaction," <i>J. Materials Science</i> , 28:6013-6020 (1993). <i>no month</i>
BH	B. J. Palmer and R. H. Hill, "Solid State Photochemistry of <i>fac</i> - $\text{Co}(\text{NH}_3)_3(\text{NO}_2)_3$ and <i>mer</i> - $\text{Co}(\text{NH}_3)_3(\text{N}_3)_3$ as Thin Films on Si(111) Surfaces," <i>J. Photochem. Photobiol. A: Chem.</i> , 72:243-249 (1993). <i>no month</i>
BI	M. Zumer, <i>Thesaurus for Liquid Crystal Research and Applications</i> , at http://www.personal.kent.edu/~slts/zeng/mala2.html . <i>not officially supplied</i>
BJ	Metallomesogens: Synthesis, Properties and Applications, Ed., J. L. Serrano, John Wiley & Sons, 1-21, 80-83, 108-111, 123-129, 144-153, and 188-192 (1996). <i>no month</i>

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3/12/03

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.



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							YES NO

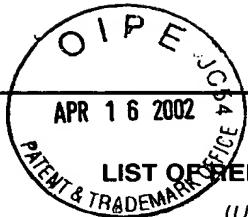
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<i>MJP</i>	BK	Blair et al., "Photochemistry of thin amorphous films of $\text{Fe}(\text{CO})_4\text{PPh}_3$ on $\text{Si}(111)$ surfaces," Journal of Organometallic Chemistry, 1998, Vol. 554, pp 63-73 <i>no month</i>
	BL	Chu et al., "Solid state photochemistry of thin films of Cr, Mo and W organometallic compounds on silicon substrates," Materials Chemistry And Physics, 1996, Vol. 43, pp 135-139 <i>no month</i>
	BM	Gao et al., "High efficiency photoresist-free lithography of UO_3 patterns from amorphous films of uranyl complexes," Journal of Materials Research, May 1998, Vol. 13 No. 5, pp 1379-89
	BN	Gao et al., "The mechanism of the photoreaction of Uranyl 1,3-diketonate complexes as thin films on silicon surfaces," Journal of Photochemistry and Photobiology A: Chemistry, 1996, Vol. 97, pp 73-79 <i>no month</i>
<i>MJP</i>	BO	Law et al., "Synthesis And Characterization Of Photochemically Produced Thin Films Of CeO_2 Films By Photoresist-Free Lithography," Materials Research Bulletin, 1998, Vol. 33 No. 1, pp 69-80 <i>no month</i>

EXAMINER	DATE CONSIDERED
<i>M JP Vasquez</i>	3/12/03

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